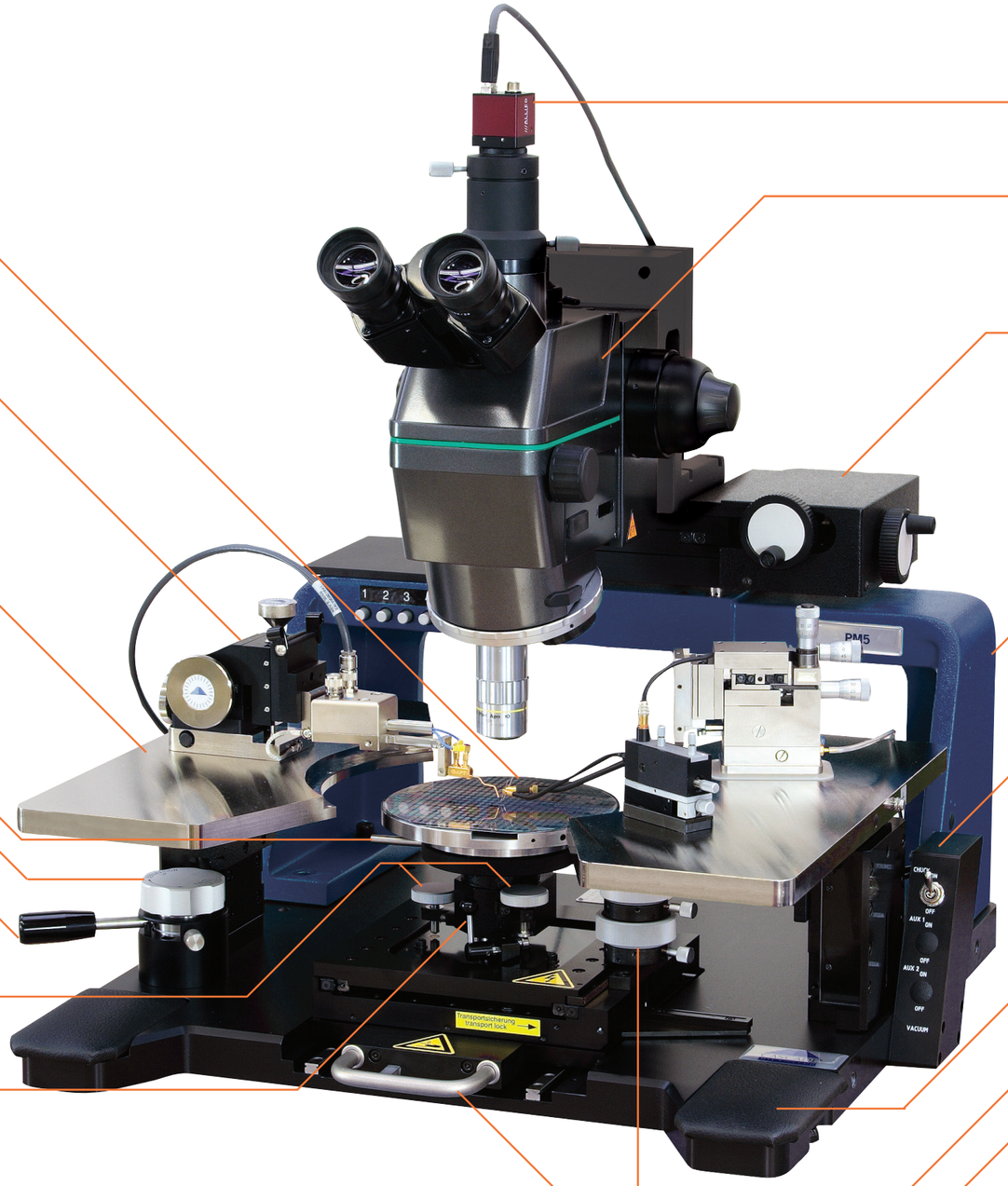
PM5

Cost-effective, manual wafer probing



Chuck
- Dedicated 150 mm chucks for general purpose, RF, mmW and triaxial measurments and high temperatures up to 400 °C available
- Excellent planarity

Positioner
- Fits with all Cascade Microtech positioners down to submicron positioning capability
- Various probe arms for accurate I-V, C-V and RF measurements available

Probe platen
- Compatible with probe card adapters
- Probe cards and positioners can be used simultaneously
- Large space to fit several positioners on each side
- Optimized RF platen for RF, mmW, load-pull and RF noise applications
- Cooled platen for chucks up to 300 °C

Chuck theta movement
- 360° theta for easy alignment
- Fine theta movement option for exact RF probe tip alignment

Platen movement
- 40 mm travel range for maximum flexibility
- System height can adapt easily from wafer to package board application

Platen separation
- 200 µm separation drive with 1 µm precision repeatable movement to contact position

Chuck Z movement
- 10 mm adjustment range for precise wafer hight adjustment

Chuck Z-separation movement
- Adjustable 3 mm chuck Z movement for simple and safe wafer loading

Camera
- C-mount camera for simple navigation and documentation

Microscope
- High-resolution microscopes (eVue™/iVista™ LC, FS70, PSM1000) for work on small features, even with laser cutter option
- Stereo microscopes for easy work with RF probe tips

Microscope movement
- 150 mm x100 mm manual movement for large area evaluation
- 50 mm x 50 mm high resolution movement for precise work with >20x objectives
- 50 mm x 50 mm motorized movement for easy navigation and heavy duty microscope integration

Microscope bridge
- Cast bridge for maximum microscope stability and low drift
- Low profile design for ergonomic microscope operation
- Alternate boom stand for stereo microscope available

Vacuum switches
- Separate switches for main chuck vacuum and up to two calibration substrates

Base platen
- Small footprint fits into small housings like glove boxes
- Easy operation of chuck and platen drives with convenient hand rest

Chuck X-Y-movement
- Precise movement allows chuck positioning with < 5 µm resolution
- Coaxial knobs for one hand operation of both axes
- Separate axis fixation for easy navigation along lines

Chuck roll-out
- 90 mm roll-out for easy wafer load, even with built-in probe card

PM5-PH-0112

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